

FIG. 1

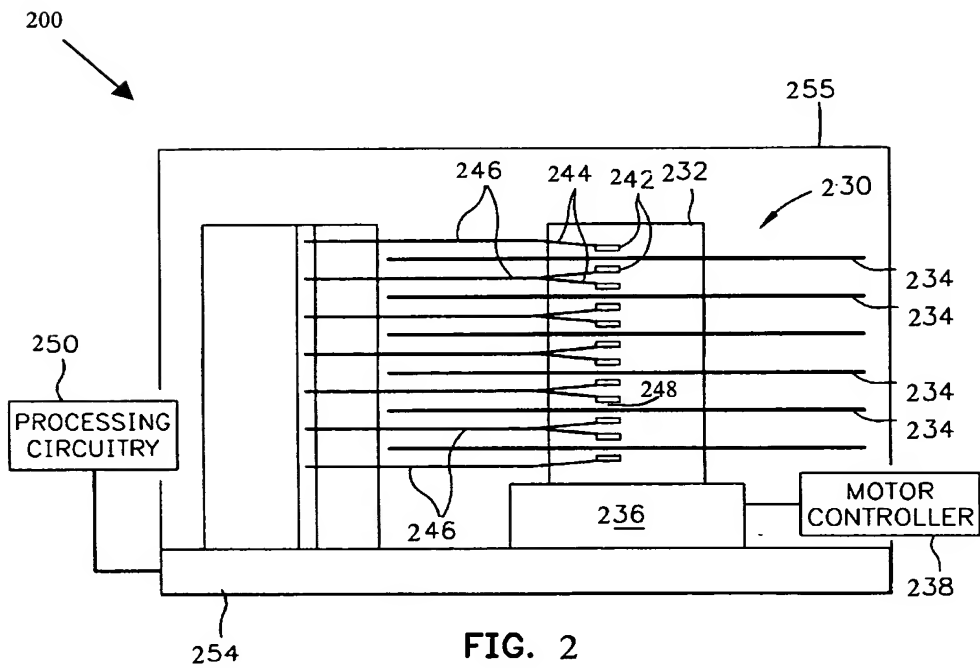


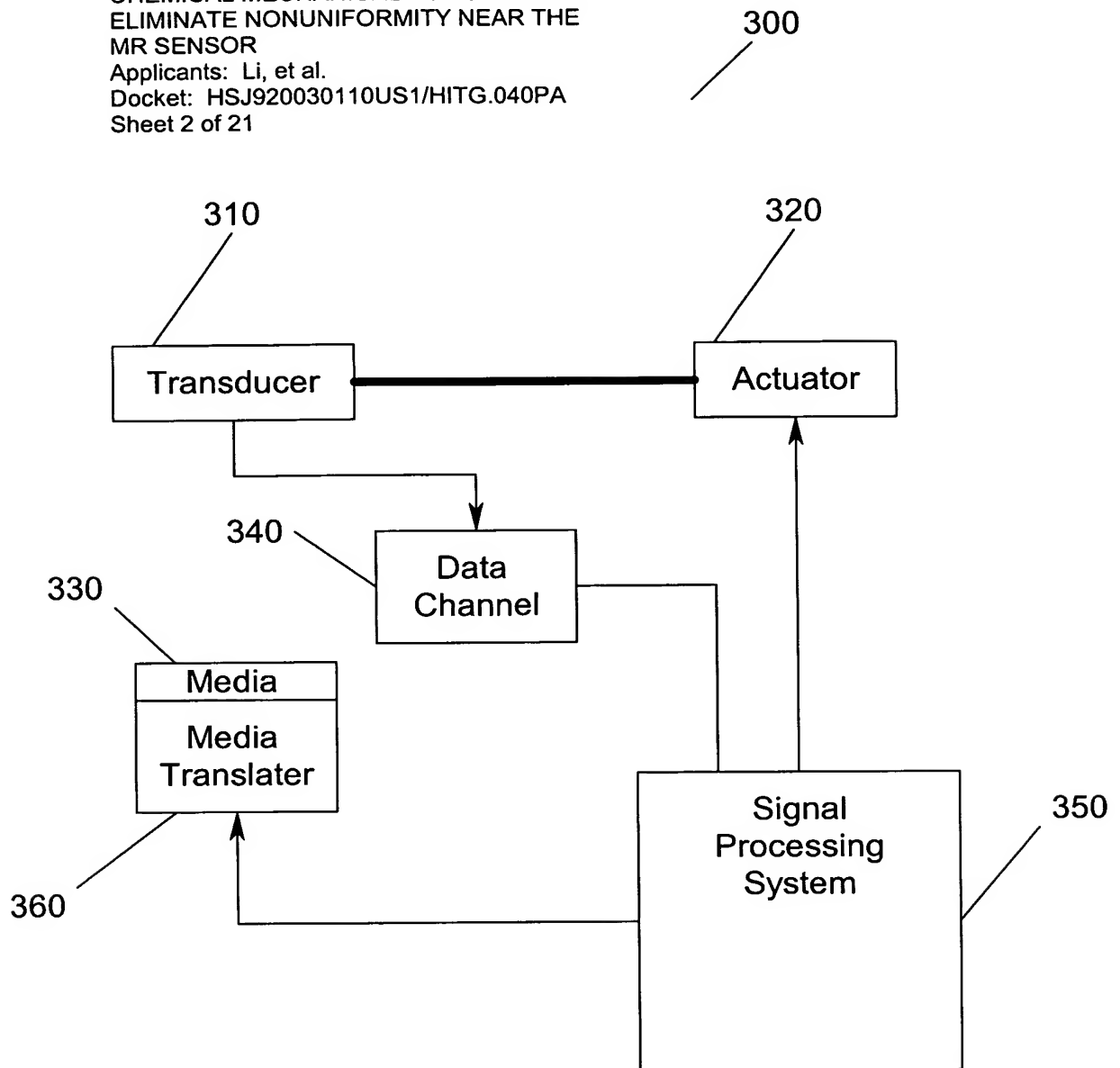
FIG. 2

Title: METHOD FOR FORMING A READ  
TRANSDUCER BY ION MILLING AND  
CHEMICAL MECHANICAL POLISHING TO  
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**Fig. 3**

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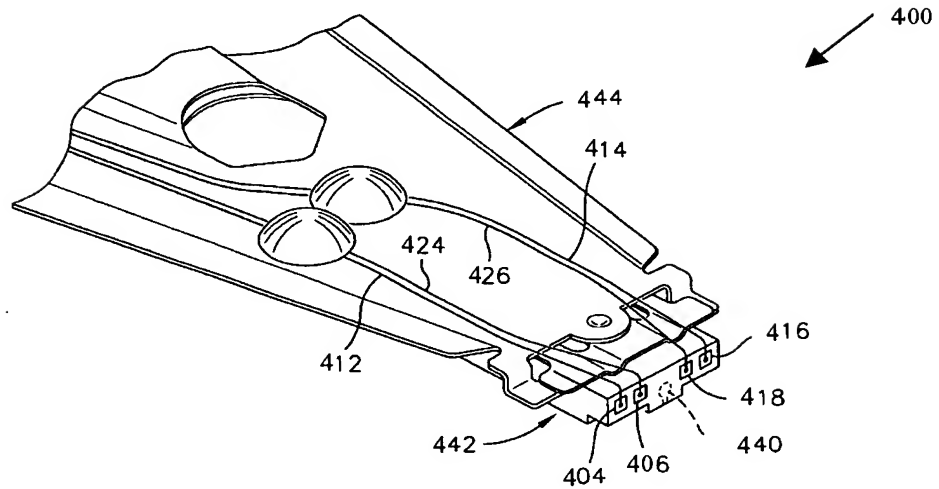


Fig. 4



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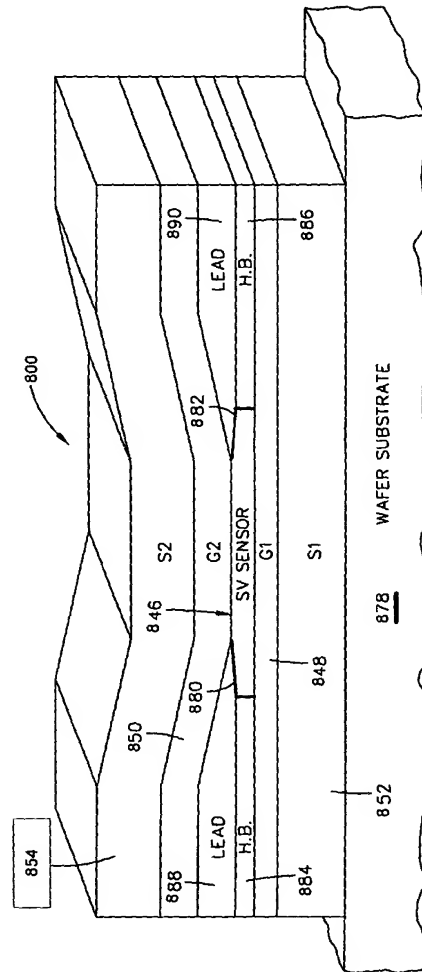


Fig. 8  
(ABS)

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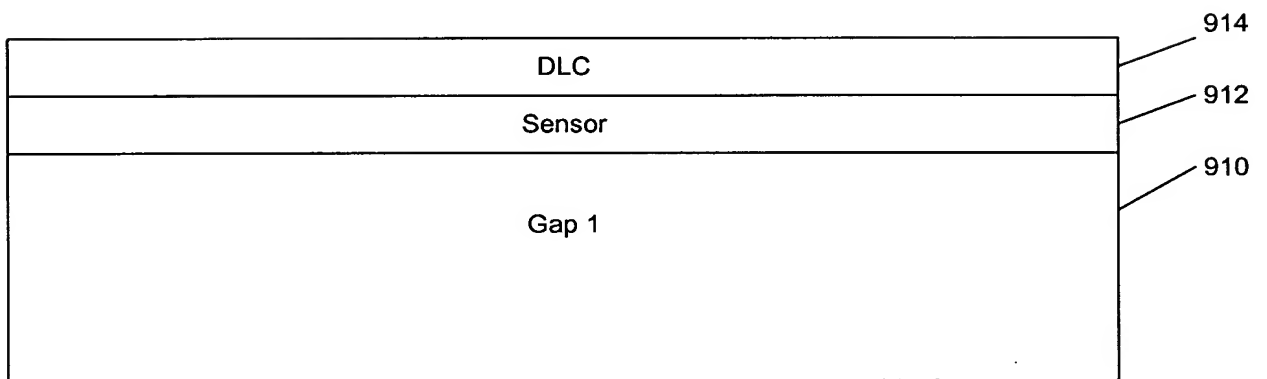


Fig. 9

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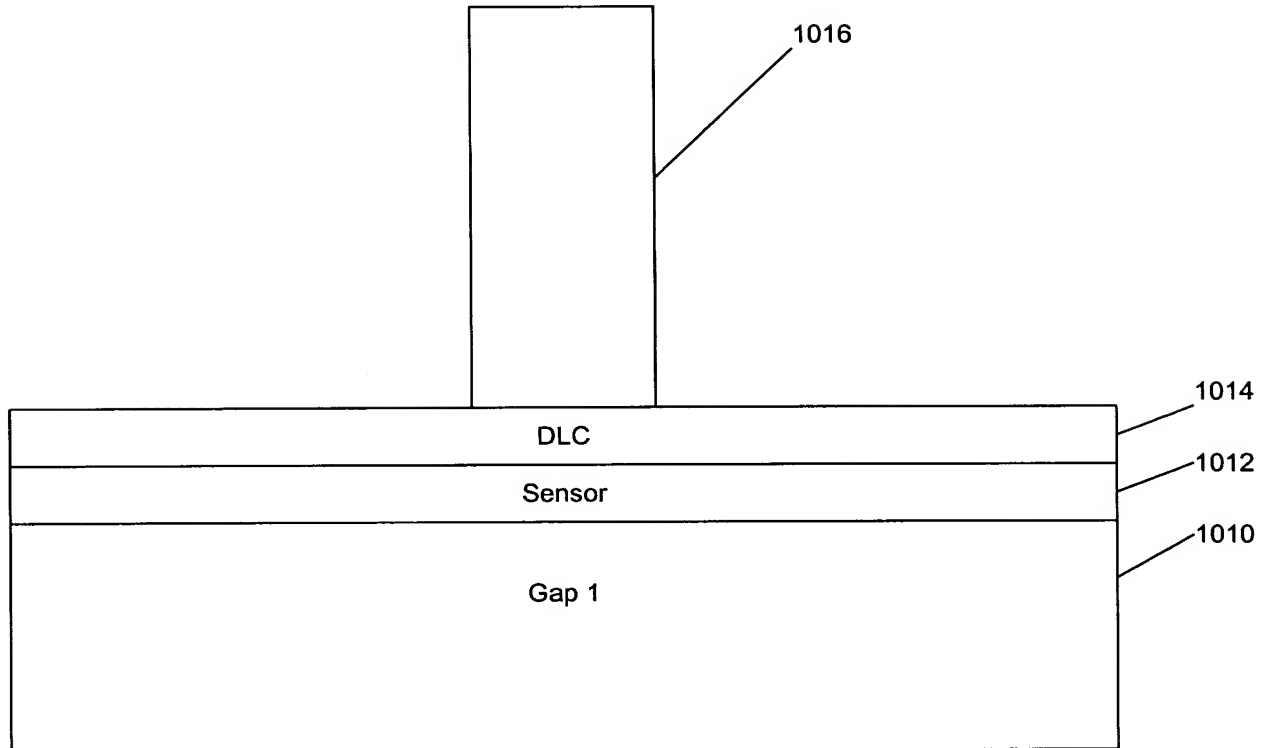


Fig. 10

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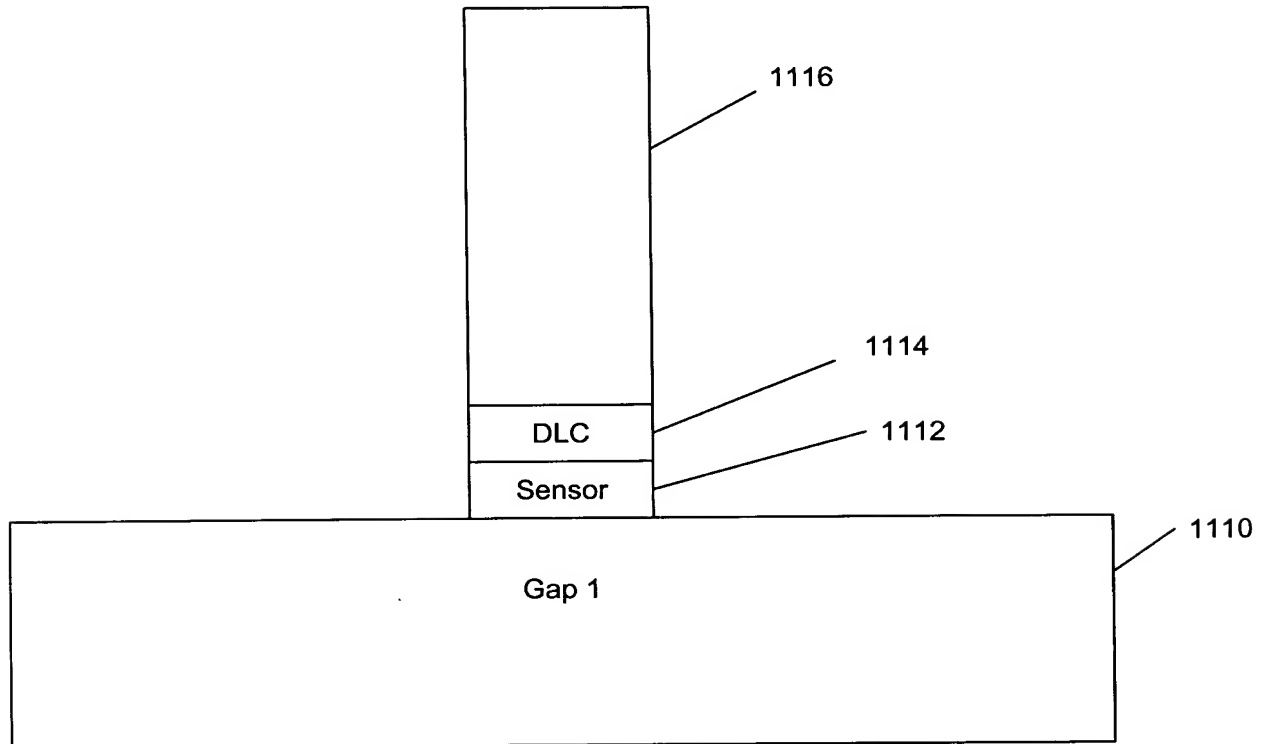


Fig. 11



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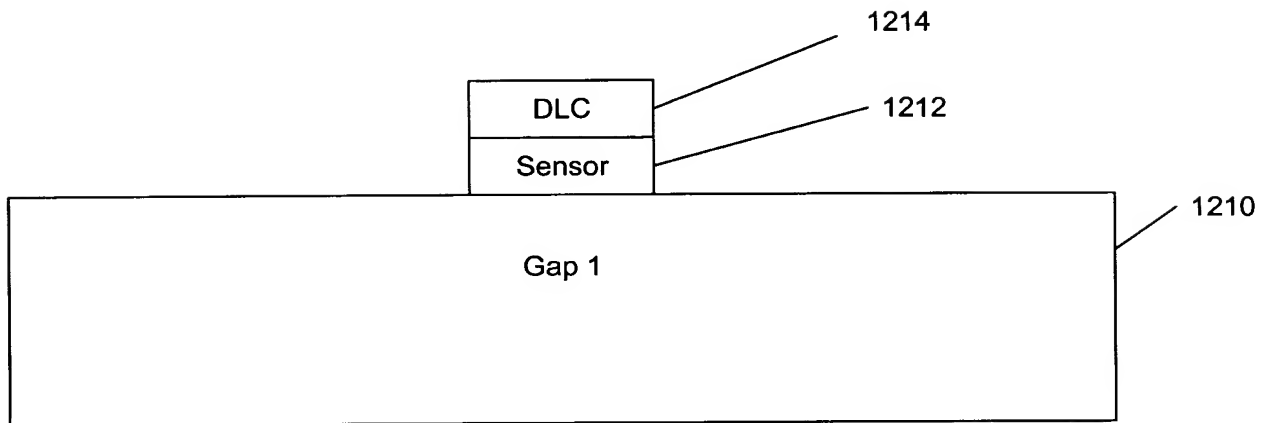


Fig. 12

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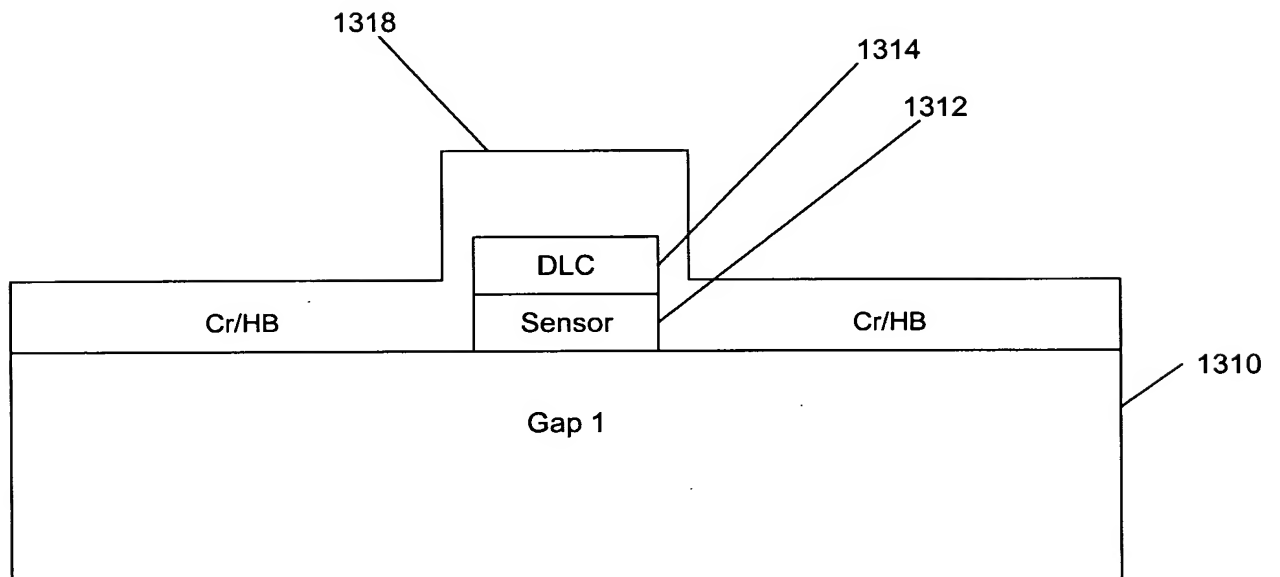


Fig. 13

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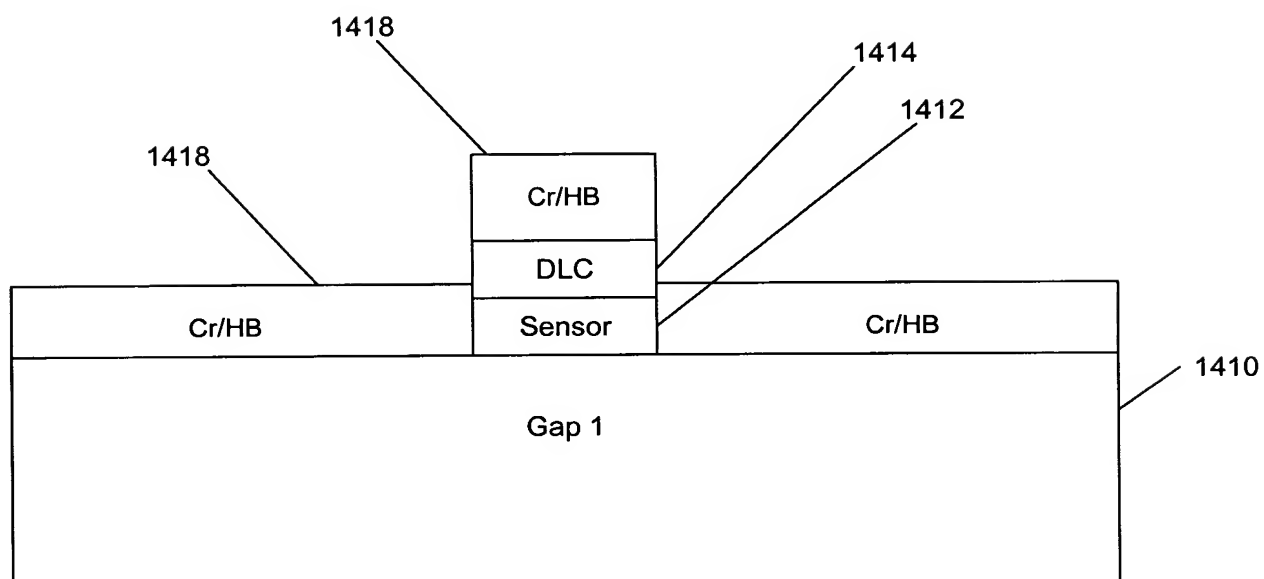


Fig. 14

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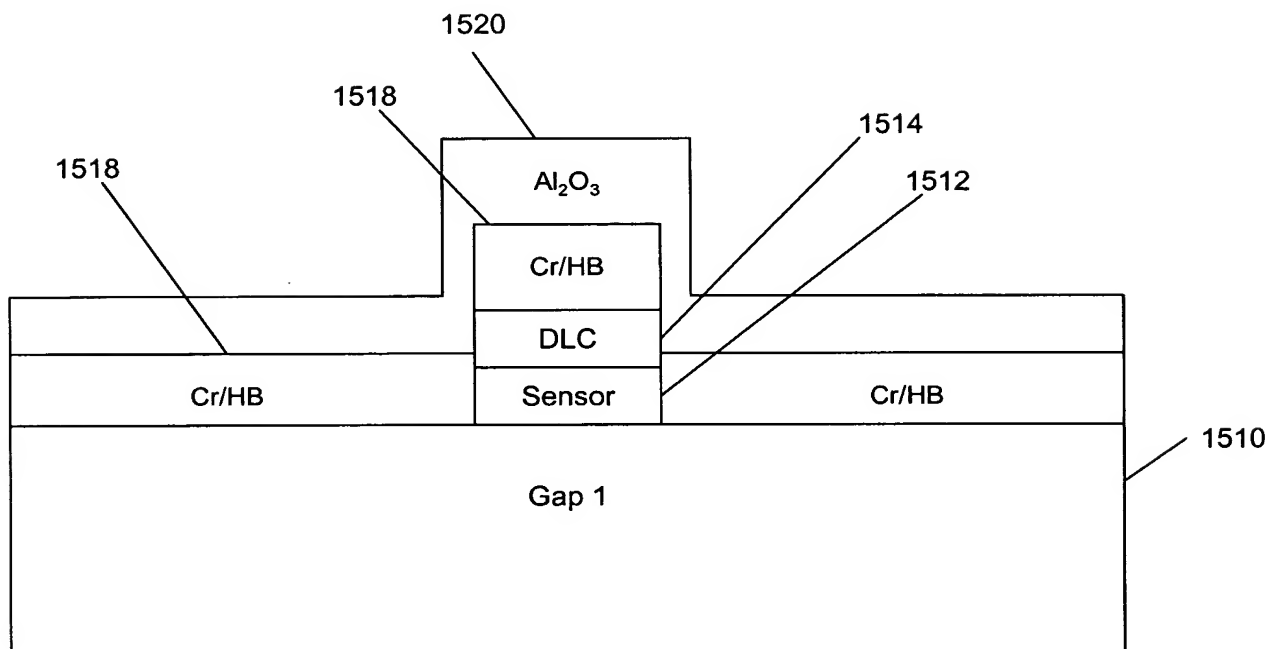


Fig. 15

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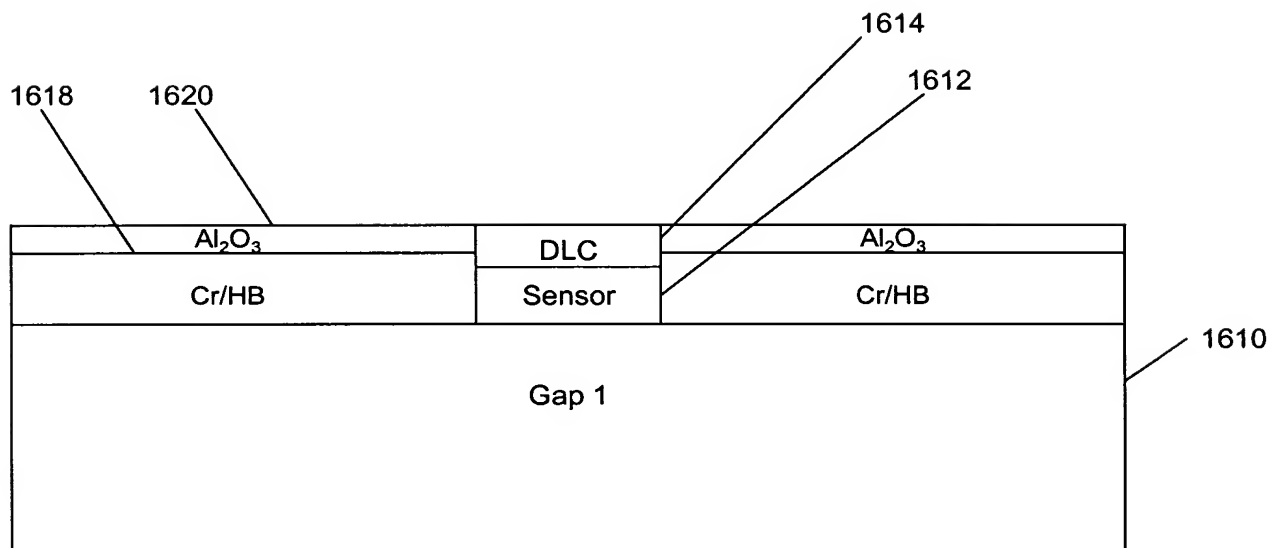


Fig. 16

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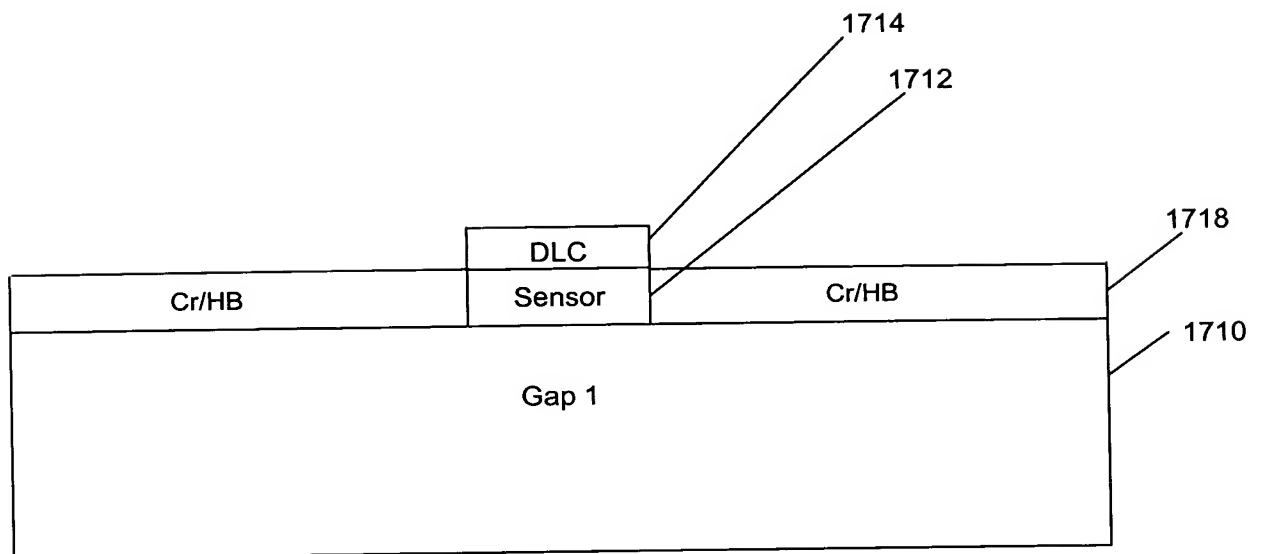


Fig. 17

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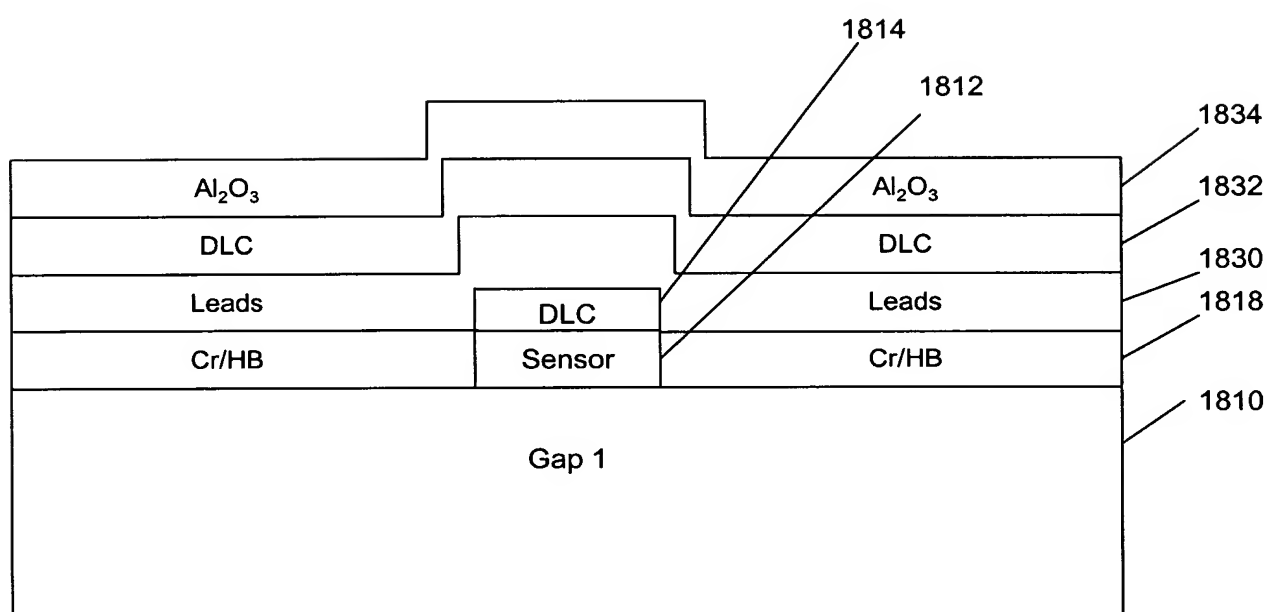


Fig. 18

Title: METHOD FOR FORMING A READ  
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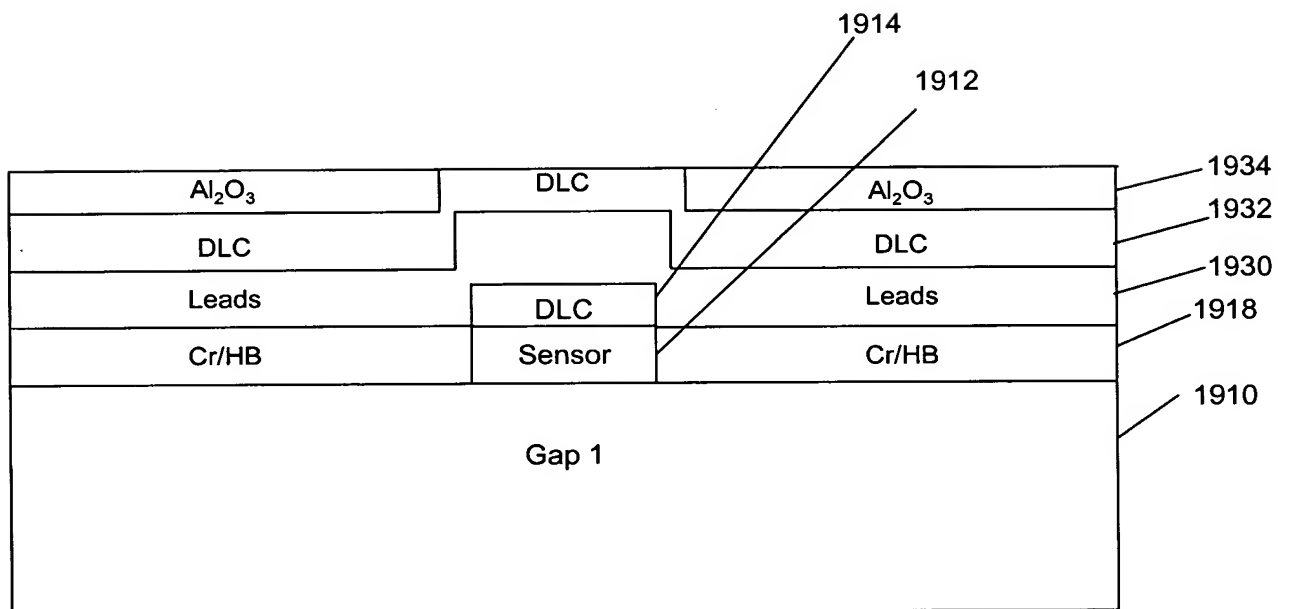


Fig. 19



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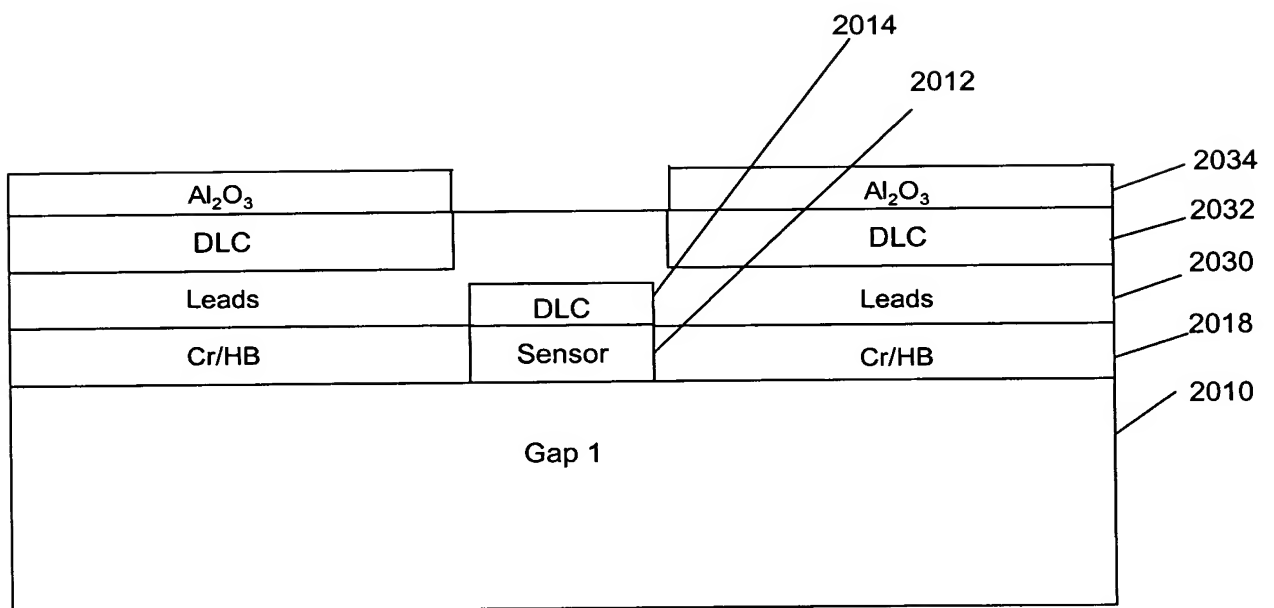


Fig. 20

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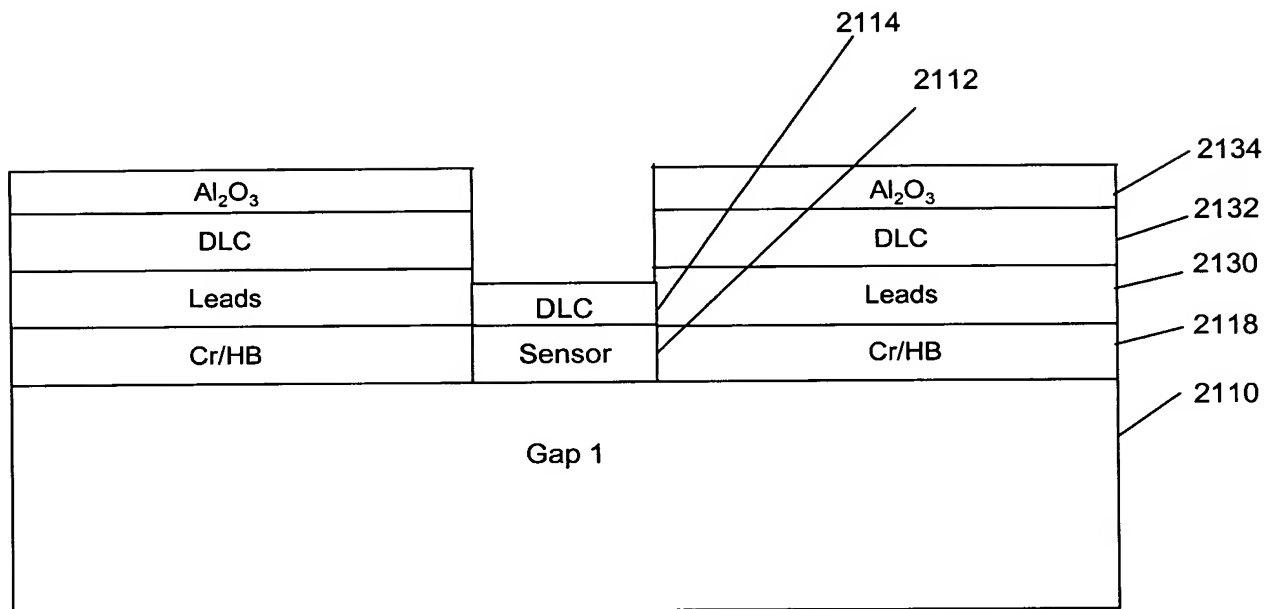


Fig. 21

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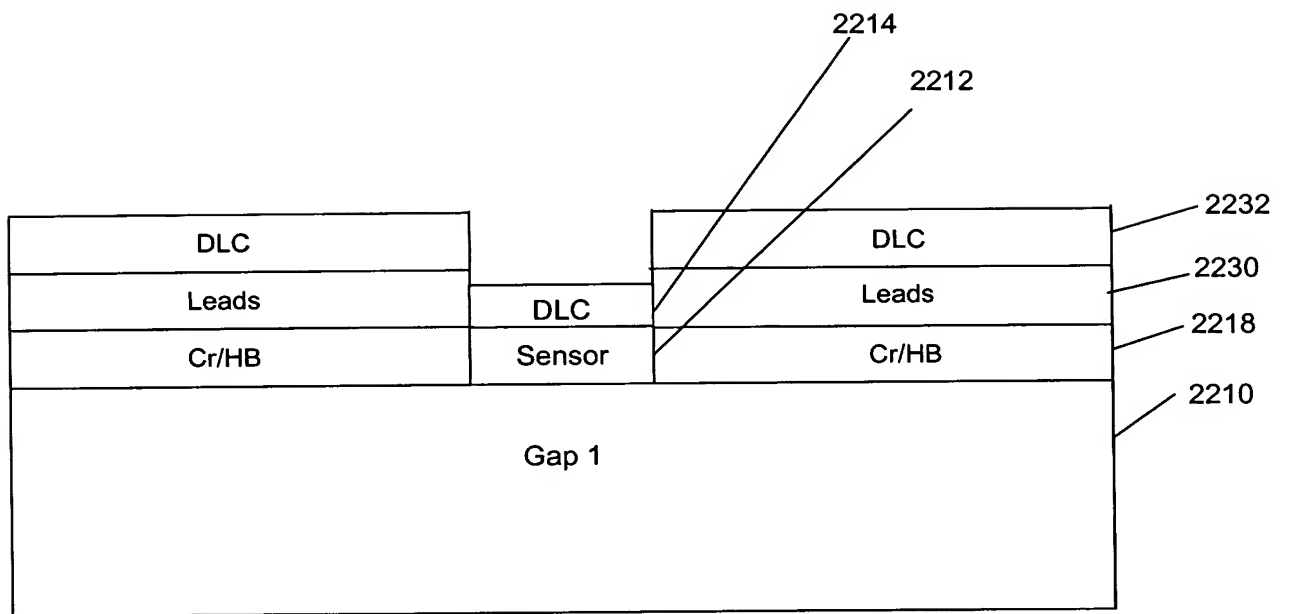


Fig. 22

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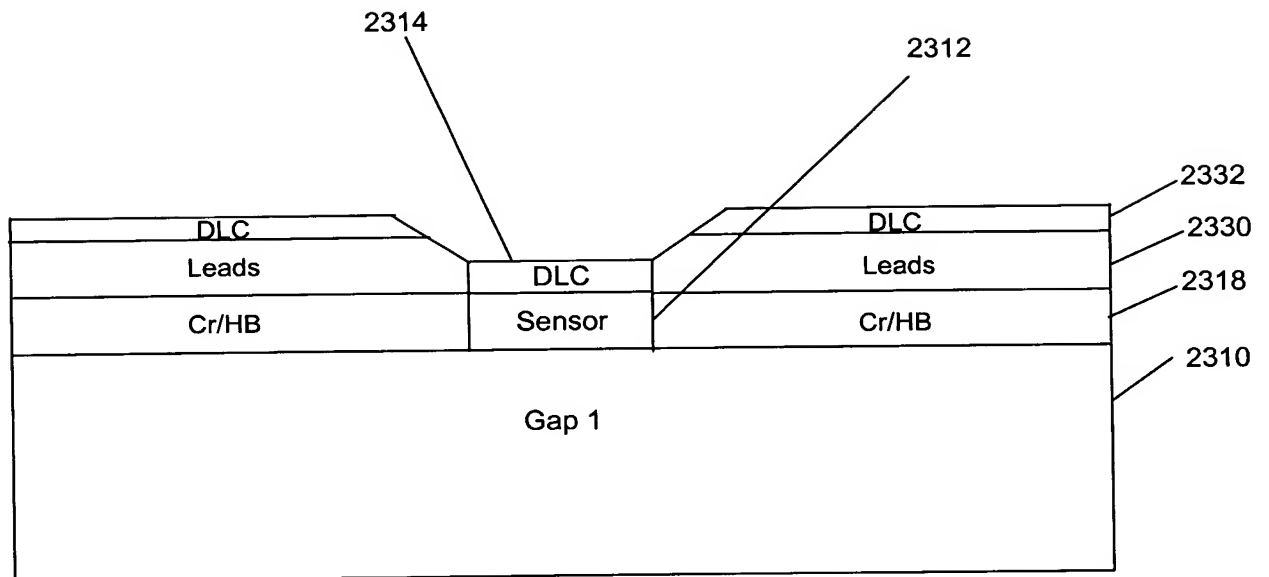


Fig. 23

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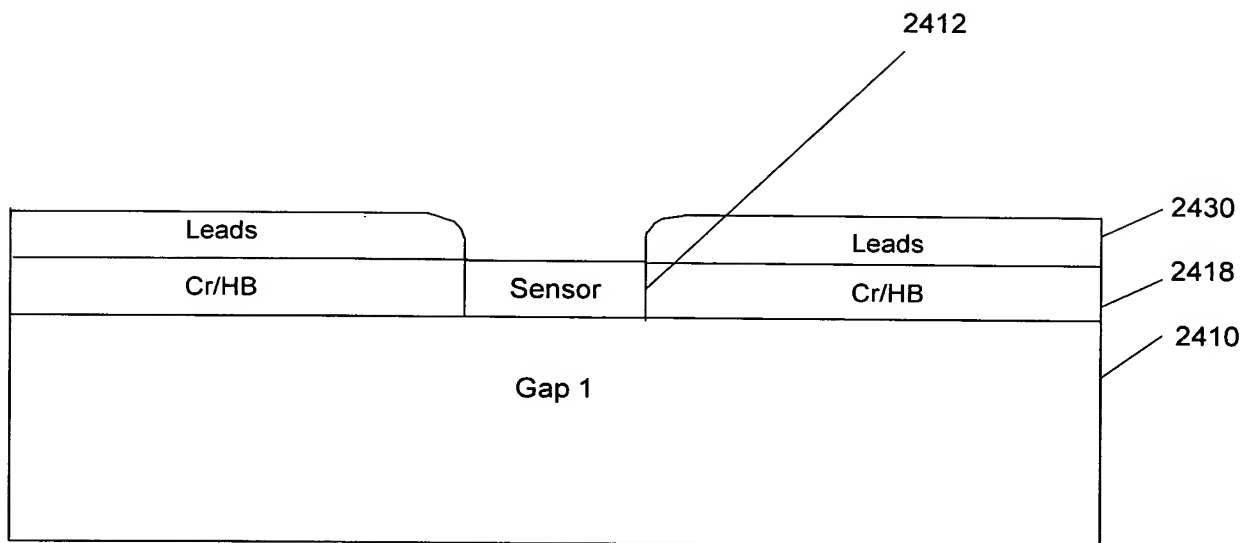


Fig. 24